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PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 1753**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM FORMATION, METHOD FOR
ELECTRODE FORMATION, AND APPARATUS FOR ELECTRODEPOSITED FILM
FORMATION

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the July 14, 2004, Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.